

Tool ID: 324  
Tool Location: 114

## Equipment Information Sheet

# Seki Diamond CVD

**Manager: Phil Infante 607-254-4926** Calls to staff phones will be automatically forwarded to their cell phones during accessible hours. At other times leave a message or send them an email.

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### SAFETY

### USAGE RESTRICTIONS

### SCHEDULING/SIGN-UP RESTRICTIONS

*Minimum Tool Time: 60 minutes*

### MATERIALS COMPATIBILITY CATEGORY

#### Tool Category 1: Restrictd Silicon Based Materials Only

Allowed	Not Allowed
Silicon Based Materials only (Si, SiC, SiO <sub>2</sub> substrates)	No Evaporated, Sputtered, or Spin on Films
All Furnace grown or deposited films	No ALD films
PECVD Films	No Metal or Organic Films
	No Glass Substrates
	No III/V Compound Semiconductors
	No Deep Silicon Etched Samples (versaline, Unaxis)
	No Organic/Biology Molecules prepared-with or without Salt buffers

### Additional Material Restrictions and Exceptions

*Last Updated: 04/17/2026*